

# Polyimide Thermal Micro Actuator

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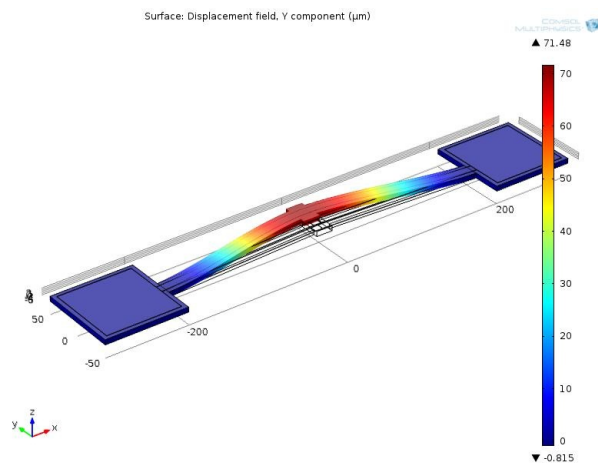
## Abstract

In this work we are simulating a chevron actuator using the materials used in our MEMS Fabrication process using Polyimide as the structural material. The aim is to choose the most appropriate design parameters to get the largest possible in-plane displacement. The comparison between the different possible configurations will reveal the optimal parameters. Figure 1 shows a simulation of a basic chevron actuator.

## Reference

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## Figures used in the abstract



**Figure 1:** Simulation of a typical chevron actuator using gold as the conducting layer.